

In the Claims:

No amendments have been made to the claims in this response.
Following is a complete listing of the claims and their status:

1. (Cancelled)
2. (Cancelled)
3. (Cancelled)
4. (Cancelled)
5. (Cancelled)
6. (Cancelled)
7. (Cancelled)
8. (Previously presented) The apparatus of claim 15, wherein said means for preventing retrograde movement includes at least one resilient prong arranged within said track assembly channel to prevent movement of a wafer in said second direction and to deflect as a wafer passes said prong in said first direction.
9. (Previously presented) The apparatus of claim 15, wherein said means for preventing retrograde movement includes a plurality of resilient prongs spaced along the length of said track assembly channel from said introduction end to said discharge end.

10. (Previously presented) The apparatus of claim 15, wherein said plurality of resilient prongs are provided in opposing pairs of prongs disposed on opposite sides of said track assembly channel.

11. (Previously presented) The apparatus of claim 15, further comprising an advancement gun supporting said track assembly and having a manually operable trigger operably coupled to said advancement mechanism so that depressing said trigger slides said advancement mechanism in said first direction within said pusher channel.

12. (Original) The apparatus of claim 11, wherein:
said advancement gun includes a housing; and
said trigger is pivotably mounted within said housing.

13. (Previously presented) The apparatus of claim 12, wherein said advancement gun includes a linkage coupled between said trigger and said advancement mechanism, said linkage configured to translate pivoting of said trigger into linear movement of said mechanism within said pusher channel.

14. (Original) The apparatus of claim 12, wherein:
said advancement mechanism includes a rack gear; and
said trigger includes a clock gear arranged to mesh with said rack gear as said trigger is pivoted.

15. (Previously presented) An apparatus for the sequentially inserting wafers into a body space of a patient, the apparatus comprising:

a track assembly defining a channel from an introduction end configured to receive wafers, to a discharge end adapted to be positioned within the body space, said channel configured to sequentially receive the plurality of wafers therein and including

a first track defining a wafer channel opening at said introduction end adapted to receive wafers therethrough; and

a second track coupled to said first track and defining a pusher channel;

an advancement mechanism slidably disposed within said pusher channel of said track assembly and operable on a wafer within said wafer channel to advance the wafer in a first direction along said wafer channel toward said discharge end; and

means for preventing retrograde movement of a wafer within said wafer channel in a second direction opposite said first direction.

16. (Original) The apparatus of claim 15, wherein said advancement mechanism includes a portion slidably disposed within said pusher channel and at least one finger projecting from said portion into said wafer channel to push a wafer disposed within said wafer channel.

17. (Original) The apparatus of claim 15, wherein:
said pusher channel defines discharge opening at said discharge end for discharge of a wafer into the body space;

said wafer channel communicates with said pusher channel adjacent said discharge end; and

said track assembly includes means for diverting a wafer from said wafer channel into said pusher channel as the wafer is conveyed along said wafer channel.

18. (Original) The apparatus of claim 17, wherein said means for diverting includes a spring arm mounted within said wafer channel and arranged to guide a wafer from said wafer channel to said pusher channel.

19. (Original) The apparatus of claim 17, wherein said advancement mechanism includes:

a portion slidably disposed within said pusher channel and arranged to push a wafer within said pusher channel to said discharge opening; and

at least one finger projecting from said portion into said wafer channel to push a wafer disposed within said wafer channel.

20. (Previously presented)The apparatus of claim 15, further comprising a cartridge configured to carry a plurality of wafers to be inserted into the body space, said cartridge operably coupled to said track assembly so a wafer from said plurality of wafers enters said introduction end of said track assembly.